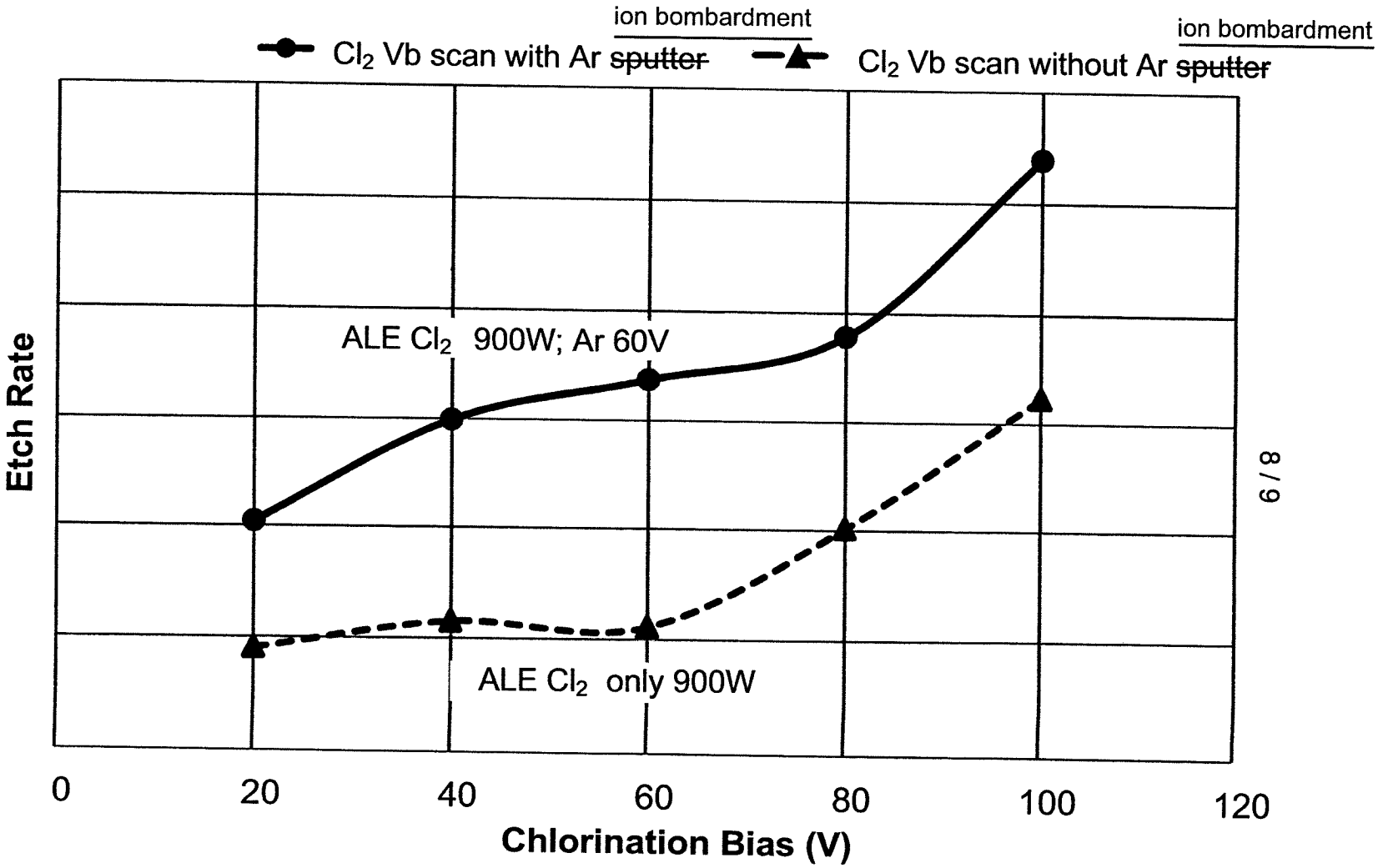
ion bombardment
Cl_2 Vb scan with Ar ~~sputter~~
ion bombardment
Cl_2 Vb scan without Ar ~~sputter~~
ALE Cl_2 900W; Ar 60V
ALE Cl_2 only 900W
Etch Rate
0
20
40
60
80
100
120
Chlorination Bias (V)

FIG. 8